

 JUL 25 2005 INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>		Docket Number (Optional) 15789-2	Application Number 10/840,134
		Applicant(s) GLENN CLARKE ET AL.	
		Filing Date 05/06/2004	Group Art Unit 2872

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
TR		2005/0110999	05/26/05	Erdogan et al.	356	417	
TA		6,809,859	10/26/04	Erdogan et al.	359	359	
TR		4,142,958	03/06/79	Wei et al.	204	192	
TR		4,793,908	12/27/88	Scott et al.	204	192.26	
TA		6,649,208	11/18/03	Rodgers	427	10	
TR		6,704,130	03/09/04	Ford et al.	359	245	
TR		5,656,138	08/12/97	Scobey et al.	204	192.12	
TR		5,512,131	04/30/96	Kumar et al.	156	655.1	

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	TRANSLATION Yes No

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

TR	Becker, J., "Ion-Beam Sputtering," Handbook of Optical Properties, Vol. 1, Thin Films for Optical Coatings, Ed. By R.E. Hummel and K.H. Guenther, Chapter 7, pp. 189-211, (CRC Press, Boca Raton, 1995)	
RA	Macleod, H. Angus, "Thin-Film Optical Filters," 3 rd Ed., Institute of Physics (2001)	
TR	Macleod, H.A., "Turning value monitoring of narrow-band all-dielectric thin-film optical filters," Optica Acta, Vol. 19, pp. 1-28 (1972)	
TA	Press, W.H., et al., The Levenberg-Marquardt method implemented under the name "mrqmin()", Numerical Recipes in C: The Art of Scientific Computing, 2 nd ed., Chapter 15, pp. 683-688 (1995)	
TR	Martin, P.J. et al., "Ion-beam-assisted deposition of thin films," Applied Optics, Vol. 22, No. 1, pp. 178-184 (1983)	
TR	"Interference Filters," Melles Griot, pp. 13.25-13.29	

Examiner Signature 	Date Considered 1/5/06
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

Form PTO-A820 (also form PTO-1449)

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<i>FP</i>	J.M.E. Harper, "Ion Beam Deposition," in <i>Thin Film Processes</i> , Ed. by J.L. Vossen and W. Kern, pp. 175-206 (Academic Press, New York, 1978).	
<i>FP</i>	U.J. Gibson, "Ion-Beam Processing of Optical Thin Films," in <i>Physics of Thin Films</i> , Vol. 13, Ed. by G. Hass and M.H. Fancombe, pp. 109-150 (Academic Press, New York, 1978).	
<i>FP</i>	J.M.E. Harper et al., "Modification of Thin Film Properties by Ion Bombardment During Deposition," in <i>Ion Bombardment Modification of Surfaces</i> , Ed. by O. Auciello and R. Kelly, from <i>Beam Modification of Materials</i> , Vol. 1, pp. 127-162 (Elsevier, Amsterdam, 1984).	
<i>FP</i>	W.H. Teukolsky et al., <i>Numerical Recipes</i> , "Numerical Recipes in C: The Art of Scientific Computing," 2 nd ed., Cambridge University Press, Cambridge, Chapter 15.7, pp. 699-706 (1995).	

Examiner Signature

Date Considered

15/04

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